

Form PTO 1449 (Modified)		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY DOCKET NO. 240896US2S		SERIAL NO. NEW APPLICATION	
LIST OF REFERENCES CITED BY APPLICANT		APPLICANT					
		Naofumi NAKAMURA, et al.		FILING DATE HEREWITH		7/29/03	
U.S. PATENT DOCUMENTS							
EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	FILING DATE IF APPROPRIATE
<i>Mew</i>	AA	6,291,891	09/18/01	Kazuyuki HIGASHI, et al.			
	AB						
	AC						
	AD						
	AE						
	AF						
	AG						
	AH						
	AI						
	AJ						
	AK						
	AL						
	AM						
	AN						
FOREIGN PATENT DOCUMENTS							
		DOCUMENT NUMBER	DATE	COUNTRY	<i>Class / Sub Class</i>	TRANSLATION	
	AO					YES	NO
	AP						
	AQ						
	AR						
	AS						
	AT						
	AU						
	AV						
OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, etc.)							
<i>Mew</i>	AW	Kelly H. BLOCK, et al., "Integration of CMP with Low-k Materials", SEMICONDUCTOR INTERNATIONAL, June 2002, pgs. 115-122					
	AX						
	AY						
	AZ	<input type="checkbox"/> Additional References sheet(s) attached					
Examiner <i>Mew</i>				Date Considered 12/1/04			
*Examiner: Initial if reference is considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.							